

Abstract

A method and apparatus for the high speed analysis of precision surfaces (2) utilises a systematic irradiating of the surface (4) with a beam of light and detection of changes in the optical properties of light reflected from the surface to locate abnormalities (4a). The position of the detected abnormalities (4a) is indexed and a high resolution imaging device such as an atomic force microscope probe (8) is positioned for imaging and analysis of the abnormality (4a).

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